

AMENDMENTS TO THE CLAIMS:

Please amend Claims 19-22, 24, 25, and 27 as follows, and add new Claims 28 and 29.

1-18 (Cancelled)

Sub. C1
19
~~19.~~

(Currently amended) A liquid discharge head, comprising:
a plurality of discharge ports for discharging liquid;
a plurality of liquid flow paths communicated with each of said discharge ports to supply liquid to each of said discharge ports;
a substrate provided with heat generating members for creating a bubble in the liquid;
a movable member arranged in each of said plural liquid flow paths, the movable member having a free end on said discharge port side to face said heat generating member; and
a pedestal portion formed on said substrate for supporting said movable member,
said movable member having a property of being curved by heat, and ~~the~~ a portion corresponding to ~~the~~ a movable range being separated by heating from said substrate.

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20.

(Currently amended) A liquid discharge head, comprising:
a plurality of discharge ports for discharging liquid;
a plurality of liquid flow paths communicated with each of said discharge ports to supply liquid to each of said discharge ports;
a substrate provided with heat generating members for creating a bubble in the liquid;
a movable member arranged in each of said plural liquid flow paths; each and having the a free end on said discharge port side to face said heat generating member; and
a pedestal portion formed on said substrate for supporting said movable member,
the a portion of said movable member corresponding to the a movable range being separated from said substrate by means of the an inner stress and the a function of the a releasable layer formed on said substrate.

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21.

(Currently amended) A liquid discharge head, comprising:
a plurality of discharge ports for discharging liquid;
a plurality of liquid flow paths communicated with each of said discharge ports to supply liquid to each of said discharge ports;
a substrate provided with a heat generating member for creating a bubble in the liquid;
a movable member arranged in said plural liquid flow paths, the movable member having a free end on said discharge port side to face said heat generating member; and

a pedestal portion formed on said substrate for supporting said movable member,

the a portion of said movable member corresponding to the a movable range being provided with a recessed part on the portion adjacent to said pedestal portion.

6/22. (Currently amended) A liquid discharge head having a substrate according to Claim 25, comprising:

a discharge port for discharging liquid; and

a liquid flow path communicated with ~~each of~~ said discharge ports port to supply liquid to ~~each of~~ said discharge port;

~~a substrate provided with heat generating members for creating a bubble in liquid; and~~

a wherein said movable member is arranged in said plural liquid flow paths path, the movable member having a free end on said discharge port side to face said heat generating member, and said free end being positioned ~~on the~~ downstream of the area center of said heat generating member;

~~said movable member being formed either one of silicon nitride, diamond, amorphous carbon hydride, and silicon oxide, and being incorporated on said substrate.~~

7/23. (Original) A liquid discharge head according to Claim ~~22~~ 6/22, wherein said movable member is formed by silicon nitride with impurities being added thereto.

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24.

(Currently amended) A liquid discharge head, comprising:
according to Claim 22,

a discharge port for discharging liquid;

a liquid flow path communicated with said discharge port to supply
liquid to said discharge port;

a substrate provided with a heat generating member for creating a
bubble in the liquid; and

a movable member arranged on said substrate in said liquid flow
path, the movable member having a free end on said discharge port side to face said heat
generating member, and said free end being positioned downstream of the area center of
said heat generating member,

wherein said movable member is formed by a silicon nitride multi-layered film with the compositions being changed or impurities being added thereto.

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25.

(Currently amended) A substrate for use of in a liquid discharge head, said substrate being provided with a heat generating member for creating a bubble in the liquid; , and a cantilever type movable member arranged to face said heat generating member with a specific gap therebetween,

said movable member being formed from either one of silicon nitride, diamond, amorphous carbon hydride, and silicon oxide, and being incorporated on
fixed to said substrate.

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26. (Original) A substrate for use of in a liquid discharge head according to Claim ⁵25, wherein said movable member is formed by silicon nitride having impurities being added thereto.

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27. (Currently amended) A substrate for use of in a liquid discharge head according to Claim 25, wherein, said substrate being provided with a heat generating member for creating a bubble in the liquid, and a cantilever type movable member arranged to face said heat generating member with a specific gap therebetween, said movable member is being fixed to said substrate and being formed by a silicon nitride multi-layered film with the compositions being changed or impurities being added thereto.

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28. (New) A method for manufacturing a substrate for use in a liquid discharge head, comprising the steps of providing the substrate with a heat generating member for generating a bubble in the liquid, and with a cantilever type movable member arranged to face said heat generating member with a predetermined gap therebetween, wherein said movable member is provided on said substrate by a photolithographic method.

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29. (New) A method for manufacturing a substrate for use in a liquid discharge head according to Claim ¹⁰28, wherein the movable member is formed by any one of silicon nitride, diamond, amorphous carbon hydride or silicon oxide.